• Class 100/10 cleanroom (~100 m²) constructed in 1992/1993
• Silicon backend processing for feature sizes down to 1.2 μm
• Device minimum features: ~30nm
• Wafer size up to 200 mm (8 inch)
• Class 10,000 area for support equipment and film deposition laboratory (~150 m²)
• Laboratories for film and device characterization
National funding for research
- Plurianual Funding
- National Projects
- Grants (phD, Post-doc)
- University salaries

Budget: 50%

INESC-MN

European funding
- 40%
- EU projects

Services
- 10%
- Universities
- Industry

INESC-MN

4th UTEN Workshop
September 2011
National funding for research
- Plurianual Funding
- National Projects
- Grants (PhD, Post-doc)
- University salaries

INESC-MN

European funding
- EU projects

Industrial partners required
(SME, Large)
=> we search for Industry

Services
- Universities
- Industry

4th UTEN Workshop
September 2011
National funding for research

- Plurianual Funding
- National Projects
- Grants (PhD, Post-doc)
- University salaries

Industrial partners search us
- Research contracts
- Technology transfer
- Wafer supply

INESC-MN

European funding
- EU projects

Services
- Universities
- Industry
Research contracts INESC-MN / Industry

- CROCUS (France): 2006-2010
- PIXTRONIX (USA): 2004-2010
- Neocera (USA): 2002-2011
- Samsung (Korea): 1998-2002
- NewayTech (China): 2011-...
1st joint VC enterprise INESC-MN / Industry

INESC-MN

NewayTech (China) 2011...

VC starting 2011
INESC-MN + NewayTech

250 wafers/year, ~ 5M€

Subcontracting Iberian Laboratory (INL)